



PATENT
MIC04 P-106

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Examiner : George A. Goudreau
Group : 1763
Applicant : Imad Mahawili, PhD
Serial No. : 09/488,309
Filed : January 20, 2000
For : REACTOR WITH REMOTE PLASMA SYSTEM AND
METHOD OF PROCESSING A SEMICONDUCTOR
SUBSTRATE

Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

ELECTION

In response to the Restriction Requirement mailed January 11, 2002, having a thirty-day period of response ending February, 10, 2002, Applicant wishes to elect the following invention:

Applicant provisionally elects the species which includes ionizing nitrogen.

REMARKS

The Examiner requires an election of a single disclosed species and identifies seven (7) species; namely a fluorine based gas; N₂ gas; H₂ gas; NH₃-silane gasses; silane gas; O₂ gas; and O₂-silane gasses. As noted above, Applicant provisionally elects the species which includes nitrogen gas. The claims readable on the elected species include Claims 1-44, 47, 53, and 55-75.

The Examiner acknowledges that Claims 1-44, 53, and 55-77 are currently generic to the disclosed species. Should any one of these generic claims be allowed, Applicant will request that the non-elected species be brought back in to the case and considered along with the allowed generic claim or claims provided that they are dependent on or otherwise incorporate all the limitations of the allowed generic claim or claims.

9
3/22/02
MW
RECEIVED
MAR 04 2002
TC 1700
COPY OF PAPERS
ORIGINALLY FILED